Didier Theron

List of Publications by Year
in descending order

26 papers	642 citations	1039880 9 h-index	839398 18 g-index
26 all docs	26 docs citations	26 times ranked	789 citing authors

#	Article	IF	Citations
1	Gallium Nitride as an Electromechanical Material. Journal of Microelectromechanical Systems, 2014, 23, 1252-1271.	1.7	173
2	Amplified piezoelectric transduction of nanoscale motion in gallium nitride electromechanical resonators. Applied Physics Letters, 2009, 94, .	1.5	110
3	Electromechanical Transconductance Properties of a GaN MEMS Resonator With Fully Integrated HEMT Transducers. Journal of Microelectromechanical Systems, 2012, 21, 370-378.	1.7	82
4	12 GHz $F_{m MAX}$GaN/AlN/AlGaN Nanowire MISFET. IEEE Electron Device Letters, 2009, 30, 322-324.	2.2	55
5	Measurement Techniques for RF Nanoelectronic Devices: New Equipment to Overcome the Problems of Impedance and Scale Mismatch. IEEE Microwave Magazine, 2014, 15, 30-39.	0.7	49
6	Field Effect Transistors for Terahertz Detection and Emission. Journal of Infrared, Millimeter, and Terahertz Waves, 2011, 32, 618-628.	1.2	40
7	Quantitative impedance characterization of sub-10 nm scale capacitors and tunnel junctions with an interferometric scanning microwave microscope. Nanotechnology, 2014, 25, 405703.	1.3	22
8	High speed e-beam lithography for gold nanoarray fabrication and use in nanotechnology. Beilstein Journal of Nanotechnology, 2014, 5, 1918-1925.	1.5	21
9	Young's modulus extraction of epitaxial heterostructure AlGaN/GaN for MEMS application. Physica Status Solidi (A) Applications and Materials Science, 2014, 211, 1655-1659.	0.8	14
10	Sensitivity and accuracy analysis in scanning microwave microscopy. , 2016, , .		12
11	Gallium nitride MEMS resonators: how residual stress impacts design and performances. Microsystem Technologies, 2018, 24, 371-377.	1.2	8
12	Electric circuit model of microwave optomechanics. Journal of Applied Physics, 2021, 129, 114502.	1.1	8
13	Multi-MHz micro-electro-mechanical sensors for atomic force microscopy. Ultramicroscopy, 2017, 175, 46-57.	0.8	8
14	Bias Dependence of Gallium Nitride Micro-Electro-Mechanical Systems Actuation Using a Two-Dimensional Electron Gas. Applied Physics Express, 2012, 5, 067201.	1.1	7
15	Nonlinear Characterization and Modeling of Carbon Nanotube Field-Effect Transistors. IEEE Transactions on Microwave Theory and Techniques, 2008, 56, 1505-1510.	2.9	6
16	Multimodal imaging technology by integrated scanning electron, force, and microwave microscopy and its application to study microscaled capacitors. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2018, 36, 022901.	0.6	6
17	GaN: A multifunctional material enabling MEMS resonators based on amplified piezoelectric detection. , 2011, , .		5
18	Nanoscale Studies at the Early Stage of Water-Induced Degradation of CH₃NH₃PbI₃ Perovskite Films Used for Photovoltaic Applications. ACS Applied Nano Materials, 2020, 3, 8268-8277.	2.4	5

#	Article	IF	Citations
19	attoF MOS varactor RF measurement VNA coupled with interferometer. , 2011, , .		2
20	Near-field microscopy: Is there an alternative to micro and nano resonating cantilevers?. , 2014, , .		2
21	Improved analytical modelling and finite element verification of stressed GaN microbeam resonators by piezoelectric actuation. Journal of Micromechanics and Microengineering, 2017, 27, 095001.	1.5	2
22	Near-Field Scanning Millimeter-Wave Microscope Operating Inside a Scanning Electron Microscope: Towards Quantitative Electrical Nanocharacterization. Applied Sciences (Switzerland), 2021, 11, 2788.	1.3	2
23	Gallium nitride MEMS resonators: How residual stress impacts design and performances. , 2016, , .		1
24	Near-field scanning millimeter-wave microscope combined with a scanning electron microscope. , 2017, , .		1
25	Quantitative Error Analysis in Near-Field Scanning Microwave Microscopy. , 2018, , .		1
26	Exploring the Capabilities of Scanning Microwave Microscopy to Characterize Semiconducting Polymers. Applied Sciences (Switzerland), 2020, 10, 8234.	1.3	0